

Notice of References Cited	Application/Control No.	Applicant(s)/Patent Under Reexamination	
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	Examiner	Art Unit	Page 1 of 1
	Denise B. Anderson	2877	

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*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
*	A	US-6,687,010	02-2004	Horii et al.	356/479
	B	US-			
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	D	US-			
	E	US-			
	F	US-			
	G	US-			
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	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

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NON-PATENT DOCUMENTS

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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)

Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.